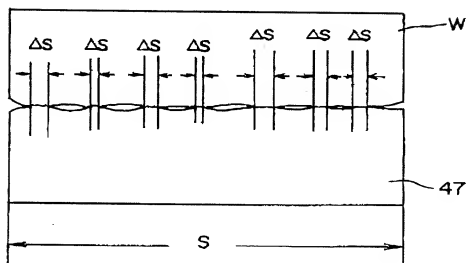


Fig.1



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Fig.2

Temperature Distribution in Wafer Surface
in Device Process Chamber

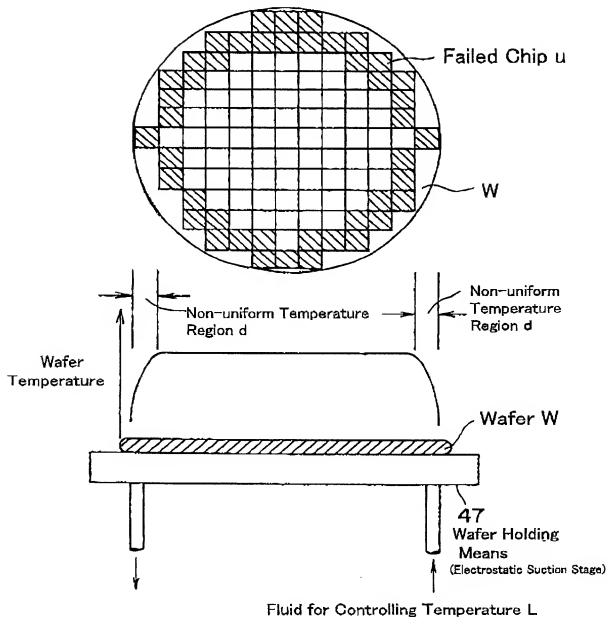


Fig 3.(A)

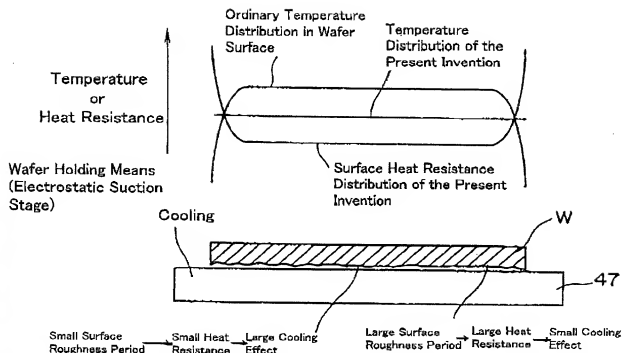
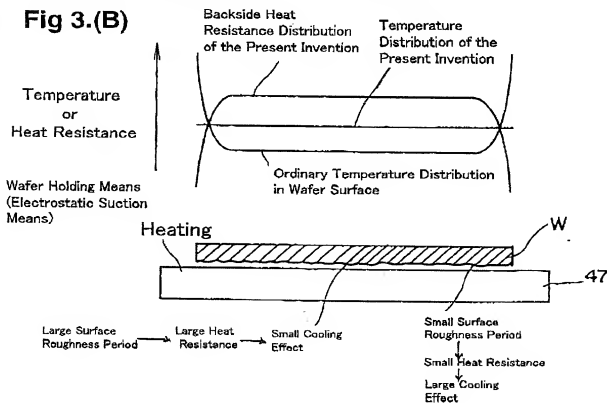
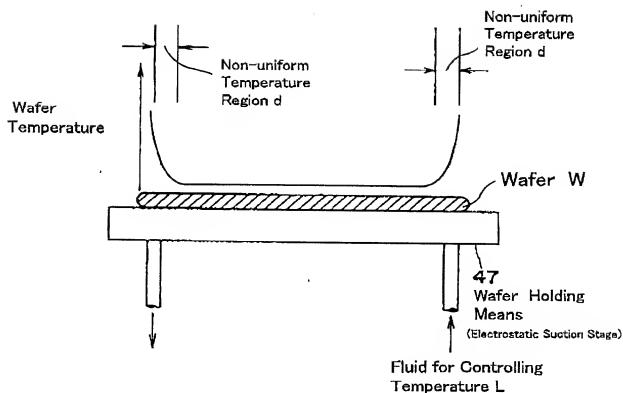


Fig 3.(B)



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Fig.4



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Fig.5 (A)

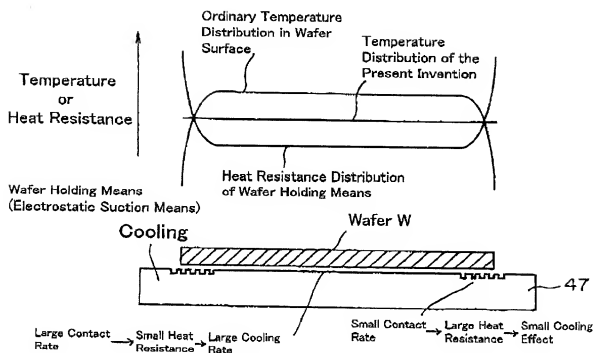
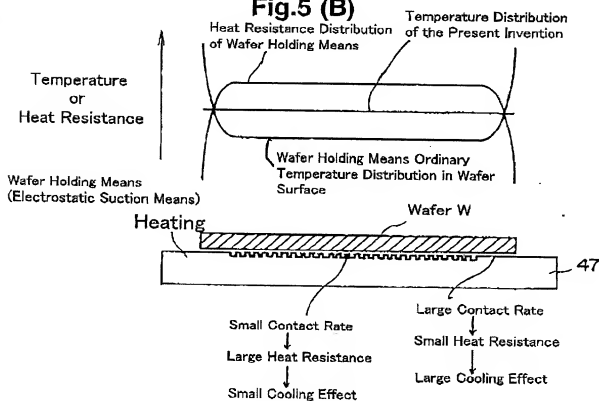


Fig.5 (B)



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Fig.6 (A)

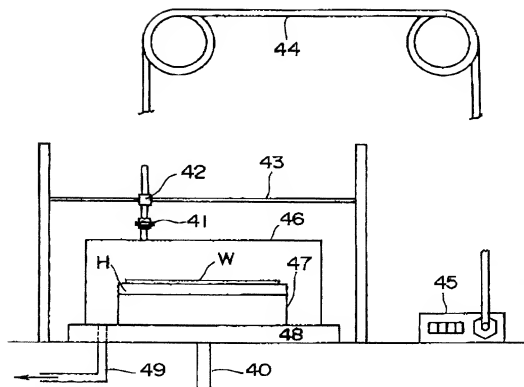
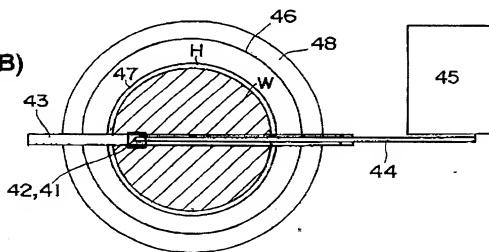


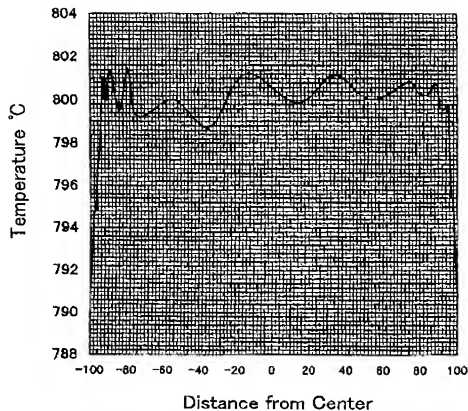
Fig.6 (B)



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Fig.7

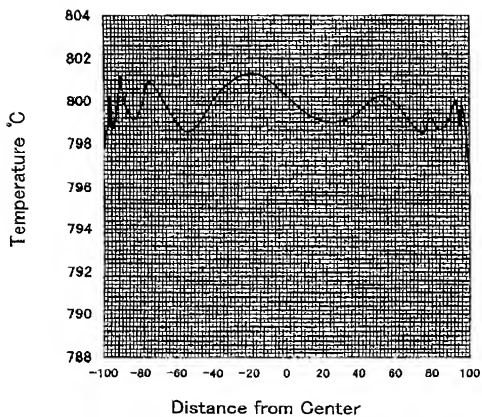
Temperature Distribution in Wafer Surface
Comparative Example



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Fig.8

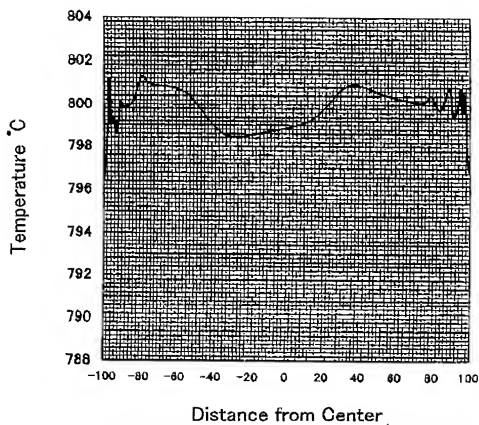
Temperature Distribution in Wafer Surface
Example 1



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Fig.9

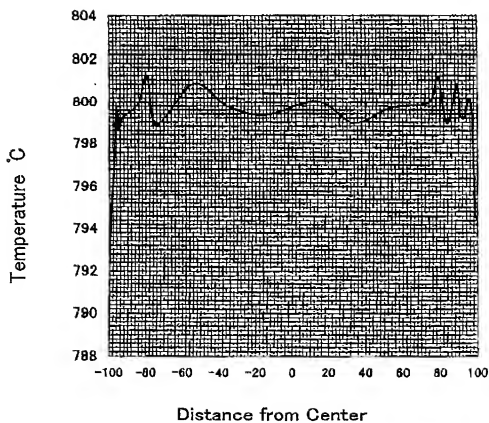
Temperature Distribution in Wafer Surface
Example 2



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Fig.10

Temperature Distribution in Wafer Surface
Example 3



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Fig.11

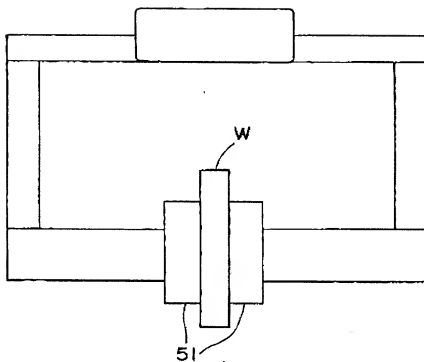


Fig.12

